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Attorney Docket No. 033082 M 275

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants	:	Kazuhide HASEBE, et al.	Confirmation No.: 6774
U.S. Serial No.	:	10/552,262	
Filed	:	October 5, 2005	
Examiner	:	Lan Vinh	
Group Art Unit	:	1792	
For	:	SILICON DIOXIDE FILM REMOVING METHOD AND PROCESSING SYSTEM	

AFTER FINAL AMENDMENT UNDER 37 C.F.R. § 1.116

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

MAIL STOP: AF

Sir:

In response the Final Office Action mailed on April 25, 2008, for which the time for response is set to expire July 25, 2008, please amend the above-identified application as set forth below and consider the following remarks.

Amendments to the claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.